PA200/AP200-BlueRay

Fastest production testing without compromising accuracy

Engineering prober screen
- Operate machine in a semi-automatic engineering mode
- Free die-to-die navigation on wafer
- Individual die testing

Operation lamp for machine status

Advanced software automation tools
- PACE - Easy to use control environment for production testing
- Powerful pattern recognition software
- Including a flexible interface for tester integration

Instrument shelf for easy access to measurement equipment

Microscope
- High-resolution optics for probe inspection, wafer navigation and alignment

Universal platen setup
- For use with DC and RF positioners and probe cards

Expert control panel
- Comfortable use without PC
- Full control of all probe stages with position feedback
- Entire system control from one panel
- Analog joystick for precise, sub-micron positioning
- Point-and-shoot navigation

Base machine
- 200 mm x/y stage for reliable 24/7 operations
- Low maintenance
- Designed for fast die stepping up to 10 die/sec
- High-accurate Z-stage for minimum scrub mark
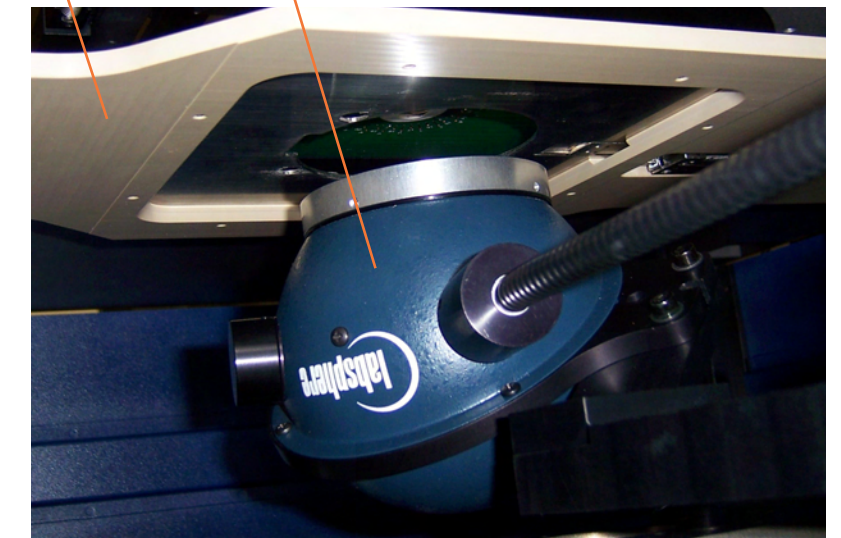
Loader module
- Universal cassette stand for substrates from 2" to 8"
- Integrated pre-aligner for flat/notch detection
- Barcode/2D Matrix code/OCR wafer code recognition
- Field upgradeable

Chuck
- Conductive chuck surface with vacuum holes for thin wafers
- Integrated AUX sites for calibration and cleaning sites
- Thermal test capability (25° C to 150° C)

PA200 DS BlueRay

Chuck for double-sided substrates

Integrated vibration isolation system
- Eliminates vibration from external sources (acoustic, architectural, etc.)
- Enhances system stability
- Reduces damage to pads, wafers and probe tips

Measurement instrumentation
- Prepared for 4" integrating sphere, fiber optics

Powerful ProberBench™ operating environment
- Stable, Linux-based controller
- Realtime PID motion controller
- Z-Profiling: Automatic wafer warpage compensation
- Integrated, reliable industrial PC for running ProberBench software

Small footprint machine table
- Integrates all prober components and supplies
- Integrated rollers

CascadeMicrotech®

PACE Prober Automation Control Environment

Prober user interface for fully-automatic production systems

Full screen GUI
- Full screen, multi page design
- Conform to SEMI E95

Equipment Status
- Current machine task
- Operation lamp status

Overview Screen

PACE - C:\PBench\Projects\6inch_____.spp

Status: Idle
8/29/2011 2:15:33 PM
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OVERVIEW

Access: Operator   Login

Machine paused

Joystick Locked

Wafer

Map View 1

Wafer Info

Lot ID:	1234
Substrate ID:	234-5634-232
Probe Card ID:	PC 456-342

Load Project
Unload Wafer

Cassette Mapping

Cassette 1

Start
Pause
Stop
Reset

Wafer Statistic

Current Die: x: **16** y: **21**

Total Dies:	57843
Tested Dies:	6365
Passed Dies:	6354
Failed Dies:	11

Reposition Needles

Measurement

Current Bin:	0
Status:	Ready for next test
Measure Time:	

F2 Overview | F3 Prober | F4 Vision | F5 Handler | F6 Recipe | F7 Setup | F8 History
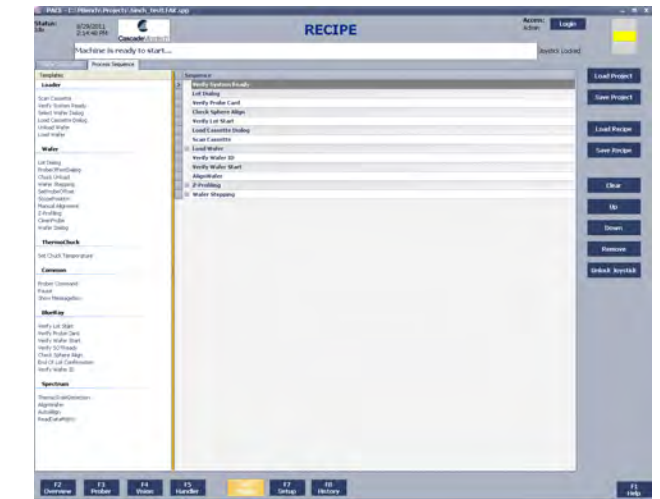
F1 Help

Vision Screen
- Embedded SPECTRUM™ Vision System
- Point-and-Shoot navigation
- Alignment training wizards

VISION

Wafermap progress
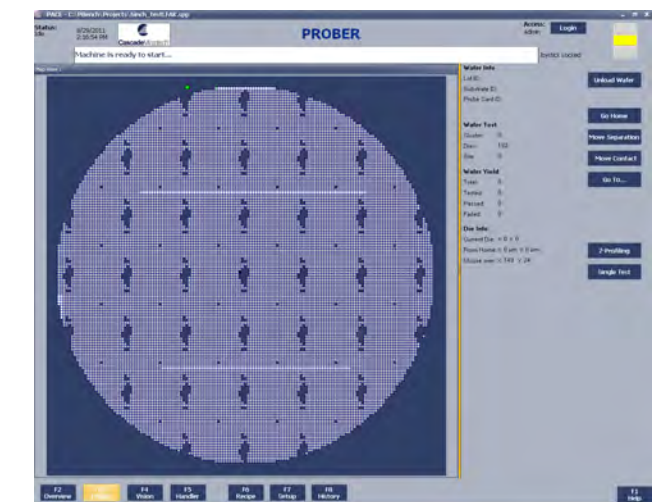- Visualization of current probelocation and test bin

Substrate ID information
- 40 mm travel range for maximum flexibility
- System height can adapt easily from wafer to package board application

Cassette Mapping
- Visualization of slots (used, cross-slotted, tested)
- Wafer-ID / slot

Pass / Fail statistics

Navigation Panel
- Easy navigation between screens using function keys

Command Panel
- Buttons enabled depending on user rights

Recipe Editor
- Simple creation of test sequence
- Build sequences by Drag'n'drop from function library to sequence list
- Easy customization

RECIPE

Engineering Prober Screen
- Operate machine in a semiautomatic engineering mode
- Free die-to-die navigation on wafer
- Individual die testing

PROBER

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